



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wunnicke, et al. Docket No.: INF-138
Serial No.: 10/781,920 Art Unit: 1756
Filed: February 20, 2004 Examiner: TBD
For: Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates

Certificate of Mailing via First Class Mail (37 C.F.R. § 1.8(a))

Date of Deposit: August 13, 2004

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Certificate of Mailing via First Class Mail (1 page)
Information Disclosure Statement (1 page)
IDS Combined Form PTO/SB/08a and 08b (1 page) citing (5) references
Copies of (4) cited references
Transmittal of Certified Copy of Priority Document (1 page)
Certified Copy of DE 103 07 523.2
Return Postcard

Respectfully submitted,

Natalie Swider
Legal Assistant

Slater & Matsil, L.L.P.
17950 Preston Rd., Suite 1000
Dallas, TX 75252
Tel: 972-732-1001
Fax: 972-732-9218



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Mail Stop: Amendment
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P. O. Box 1450
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INFORMATION DISCLOSURE STATEMENT

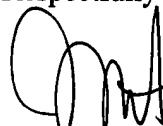
Dear Sir:

Applicants wish to bring to the attention of the Patent and Trademark Office the information noted on the enclosed combined form PTO/SB/08a & 08b that may be considered material to the examination of the above-identified application.

No fee is due at this time, as this Information Disclosure Statement is being filed pursuant to 37 C.F.R. § 1.97(b)(3), before the mailing of a first Office action on the merits.

August 13, 2004

Date

Respectfully submitted,

Ira S. Matsil
Attorney for Applicants
Reg. No. 35,272

Slater & Matsil, L.L.P.
17950 Preston Rd., Suite 1000
Dallas, TX 75252
(972) 732-1001 (phone)
(972) 732-9218 (fax)



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Commissioner for Patents
P.O. Box 1450
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Transmittal of Certified Copy of Priority Document

Dear Sir:

Attached please find a certified copy of the foreign application from which
priority is claimed for this case:

Country: Germany
Application Number: 103 07 523.2
Filing Date: February 21, 2003

Respectfully submitted,



Ira S. Matsil
Reg. No. 35,272
Attorney for Applicants

Slater & Matsil, L.L.P.
17950 Preston Rd., Suite 1000
Dallas, TX 75252
Tel: 972-732-1001
Fax: 972-732-9218



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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Use as many sheets as necessary)</i>				Complete if Known	
				Application Number	10/781,920
				Filing Date	2/20/2004
				First Named Inventor	Wunnicke, et al.
				Art Unit	1756
				Examiner Name	TBD
Sheet	1	of	1	Attorney Docket Number	INF-138

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)			
	2	WO 02/067304 A1	08-29-2002	Hyon, Man-Sok	

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	3	TANAKA, T., et al., "Mechanism of Resist Pattern Collapse during Development Process," Jpn. J. Appl. Phys. Vol. 32, Part I, No. 12B, December 1993, pp. 6059-6064.	
	4	CAO, H.B., et al., "Comparison of Resist Collapse Properties for Deep Ultraviolet and 193 nm Resist Platforms," J. Vac. Sci. Technol. B, Vol. 18, No. 6, Nov/Dec 2000, pp. 3303-3307.	
	5	DÖRFLER, H.-D, "Grenzflächen und Kolloidchemie," VCH, 1994, ISBN 3-527-29072-9, pp. 225-229	

Examiner Signature		Date Considered
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***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ***Applicant's unique citation designation number (optional).** ***See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04.** **³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3).** **⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.** **⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible.** **⁶Applicant is to place a check mark here if English language Translation is attached.**

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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